

MIT Open Access Articles

*Dual Threshold Voltage Integrated Organic
Technology for Ultralow-power Circuits*

The MIT Faculty has made this article openly available. **Please share** how this access benefits you. Your story matters.

Citation: Nausieda, I. et al. "Dual threshold voltage integrated organic technology for ultralow-power circuits." Electron Devices Meeting (IEDM), 2009 IEEE International. 2009. 1-4. © 2009, IEEE

As Published: <http://dx.doi.org/10.1109/IEDM.2009.5424345>

Publisher: Institute of Electrical and Electronics Engineers

Persistent URL: <http://hdl.handle.net/1721.1/60019>

Version: Final published version: final published article, as it appeared in a journal, conference proceedings, or other formally published context

Terms of Use: Article is made available in accordance with the publisher's policy and may be subject to US copyright law. Please refer to the publisher's site for terms of use.



Dual Threshold Voltage Integrated Organic Technology for Ultralow-power Circuits

I. Nausieda, K. Ryu, D. He, A. I. Akinwande, V. Bulović, C. G. Sodini

Microsystems Technology Laboratories, MIT, Cambridge, MA 02139, USA, nausieda@alum.mit.edu

Abstract

For the first time, we demonstrate control of organic thin-film transistor's (OTFT) threshold voltage (V_T) by modifying the gate work function. We present a near-room-temperature, fully lithographic process to fabricate integrated pentacene dual V_T OTFTs suitable for large-area and flexible mixed signal circuits. Platinum and aluminum are used as the gate metals for the high V_T (more depletion-like) and low V_T (more enhancement-like) p-channel devices, respectively. The availability of a high V_T device enables area-efficient zero- V_{GS} current source loads. We demonstrate positive noise margin inverters which use pico Watts of power and a 3 V supply. Compared to a single V_T implementation, the dual V_T inverter occupies an area that is 30x smaller, and is 17x faster. These results show that p-channel only organic technologies can produce functional and low-power circuits without integrating a complementary device.

Introduction

Organic thin-film transistors can enable large-area and flexible electronics because their low processing temperatures ensure their compatibility with polymer substrates. Although individual p-channel OTFTs have been demonstrated with impressive mobilities ($\mu_{\text{hole}} \geq 1 \text{ cm}^2/\text{Vs}$), positive noise margins in OTFT digital circuits have been difficult to achieve due to the absence of a complementary device, the value of the V_T , and the lack of resistors (1,2). We have addressed this problem by creating a dual V_T process, with the addition of only one mask to pattern a second gate metal. By using low and high work function metal gates, we are able to fabricate nominally identical devices whose V_T 's are shifted by an amount of ΔV_T . To the best of our knowledge, this is the first demonstration of OTFT V_T control by changing gate materials. The availability of two threshold voltages reduces the inverter area by 30x and increases inverter speed 17x compared to a single V_T implementation. We present positive noise margin inverters which use pico Watts of power and a near rail-to-rail ring oscillator, both powered by a 3 V supply. The 3 V V_{DD} is an order of magnitude lower than what has been reported for other photolithographic integrated organic circuits, which typically use at least 25-30 Volts (2,3). The dual V_T circuits also use 10,000x lower switching current, and 10x-20x less static power than state-of-the-art complementary organic circuits at 3 V (4).

Experimental: Process Technology

We have developed a near room-temperature, completely photolithographic dual threshold voltage process to fabricate large-area, flexible organic integrated circuits.

Dual threshold voltages are obtained by using two different gate metals: aluminum for the low (more enhancement-like) V_T device and platinum for the high (more depletion-like) V_T OTFT. The addition of a second gate metal adds only one mask compared to the conventional process.

We can write the threshold voltage equation for this system as follows,

$$V_T = \left(\Phi_{\text{gate}} - \Phi_{\text{semiconductor}} \right) - \frac{Q_I}{C_{\text{ox}}} \quad (1)$$

where Φ_{gate} and $\Phi_{\text{semiconductor}}$ are the potentials of the gate and semiconductor, Q_I the fixed charge per unit area at the gate dielectric/semiconductor interface, and C_{ox} the gate capacitance per unit area.

Although this equation is technically for the flatband voltage, since these devices operate in accumulation, OTFT literature commonly refers to this voltage as the threshold voltage. Therefore, we will refer to this quantity as V_T for consistency.

Since the gate dielectric and semiconductor deposition steps for both devices are done at the same time, we expect nominally the same $\Phi_{\text{semiconductor}}$ and Q_I/C_{ox} for the aluminum and platinum gate OTFTs. Therefore, the V_T of both devices should be shifted by the difference in gate work function. For the case of aluminum and platinum gates, theoretically we should expect a difference in threshold voltage, which we call ΔV_T , of $\sim 1.3 \text{ V}$.

The low temperature ($\leq 95^\circ\text{C}$) process is pictured in Figure 1. All processing steps are done in a class 100 clean room. The process flow produces p-channel devices with two different threshold voltages, and two metal interconnect layers. The gate metals are patterned by lift-off. Both V_T devices employ an organic polymer (parlylene-C) dielectric and pentacene as the channel material (5).

The current-voltage characteristics of fabricated devices are pictured in Figure 2. We observe that the current-voltage characteristics of aluminum and platinum gate devices are nominally identical, shifted by a threshold voltage difference, ΔV_T . Statistics of the threshold voltages of Al and Pt devices over three wafers are shown in Figure 3. A consistent ΔV_T between the Al and Pt devices of $\sim 0.6 \text{ V}$ was measured over multiple wafers and lots. We do not observe any difference

in mobility, C_{ox} , or subthreshold slope between Al-gate and Pt-gate devices. The mobility and other device parameters are consistent with what we observe in our standard Au-gate, single V_T process (6).

It was found that lift-off patterning the gates was necessary to obtain reproducible V_T 's and ΔV_T 's. Two reasons are suggested for the difference between the measured and theoretical ΔV_T . First, it is known that the presence of water on a metal surface can alter the surface potential (7,8). Contamination of the metal surfaces by processing, or residual water layers on the metal gates may lead to the effective work function difference of 0.6 V.

Dual V_T Digital Circuits

In the p-channel only OTFT technology, we can choose between using a diode-connected or zero- V_{GS} load. Since the diode-loaded inverter suffers from asymmetric voltage transfer curves and low gain, we focus our analysis on the zero- V_{GS} topology (9). Given the gate voltage dependent mobility in OTFTs, the zero- V_{GS} load must be significantly wider than the driver to achieve positive noise margins (10,11). Not only does this make the area of the inverter large, it also increases the C_{GD} of the load transistor, decreasing inverter speed. A dual threshold voltage technology solves this problem by enabling area-efficient, high output resistance zero- V_{GS} current sources. The availability of a high V_T (i.e. more depletion-like) device reduces the load's size by two orders of magnitude.

Using an inverter topology with a high V_T device as the load and with a low V_T driver, one obtains substantial area and power savings, as well as shorter propagation delays while maintaining high noise margins. The inverter was sized to maximize noise margins by locating the trip voltage at $V_{DD}/2$, and also to minimize inverter area. The inverter schematic and measured inverter transfer characteristics are shown in Figure 4. We demonstrate positive noise margin ($NM_H=0.3$ V, $NM_L=1.3$ V, $V_{DD}=3$ V) inverters using this process. The inverter transfer curve is asymmetric, since the V_T of the zero- V_{GS} load was ~ 200 mV more negative than was used in the hand calculations.

The measured dual V_T inverter uses pico Watts of power, and occupies an area that is 30 times smaller than an Al-only topology. An 11-stage ring oscillator with an output buffer was fabricated and tested. Powered by a 3 V supply, the oscillator swings near rail-to-rail (0.05 V to 2.85 V) with a propagation delay of 27 ns, as seen in Figure 5. This is one of the few near rail-to-rail integrated OTFT ring oscillators

reported in literature. Near rail-to-rail operation is necessary to accurately extract the inverter propagation delay.

These results compare favorably with state-of-the-art organic digital circuits. The dual V_T inverters here use 40x less area, 10,000x less dynamic power, and 10x-20x less static power than the 3 V shadow-masked complementary inverters reported by Klauk, et al. (4). The dual V_T inverter has a power delay product of 5.6×10^{-13} J, compared to an estimated power-delay product of 3×10^{-11} J of Klauk's 3 V inverters.

Conclusions

In summary, we have demonstrated the first dual threshold voltage integrated OTFT technology suitable for mixed signal organic circuits. This fully photolithographic technology enables area-efficient zero- V_{GS} current source loads. We have fabricated and tested digital logic using this process, and have measured positive noise margin inverters and near rail-to-rail ring oscillators using a 3 V power supply. This is the lowest V_{DD} reported for photolithographically processed organic integrated circuits. Not only does lowering V_{DD} reduce power consumption, it also improves circuit lifetime by decreasing the gate-field dependent bias-stress effects (12). Lastly, a 3 V V_{DD} could enable interfacing with silicon ICs without the requirement of level-shifting.

Acknowledgements: This work was funded in part by the FCRP Focus Center for Circuit & System Solutions (C2S2), under contract 2003-CT-888. Ivan Nausieda acknowledges financial support from the Martin Family Fellowship for Sustainability. This research has taken place at the Microsystems Technology Laboratories of MIT.

References

- (1) D. J. Gundlach, et al., *Proceedings of the 57th Device Research Conference Digest*, pp. 164-165, 1999.
- (2) E. Cantatore, et al., *IEEE Journal of Solid-State Circuits*, pp. 84-92, 2007.
- (3) M. G. Kane, et al., *IEEE Electron Device Letters*, pp. 534-536, 2000.
- (4) H. Klauk, et al., *Nature*, pp. 745-748, 2007.
- (5) I. Kymissis, et al., *IEEE Journal of Display Technology*, pp. 289-294, 2005.
- (6) I. Nausieda, et al., *IEEE Transactions on Electron Devices*, pp. 527-532, 2008.
- (7) E. E. Huber, et al., *Surface Science*, pp. 447-465, 1966.
- (8) S. Meng, et al., *Physical Review B*, pp. 195404, 2004.
- (9) S. De Vusser, et al., *IEEE Transactions on Electron Devices*, pp. 601-610, 2006.
- (10) K. Ryu, et al., *IEEE Electron Device Letters*, pp. 716-718, 2005.
- (11) T.-C. Huang, et al., *IEEE Journal of Display Technology*, pp. 206-215, 2009.
- (12) K. Ryu, *Ph.D. thesis, MIT*, 2009.

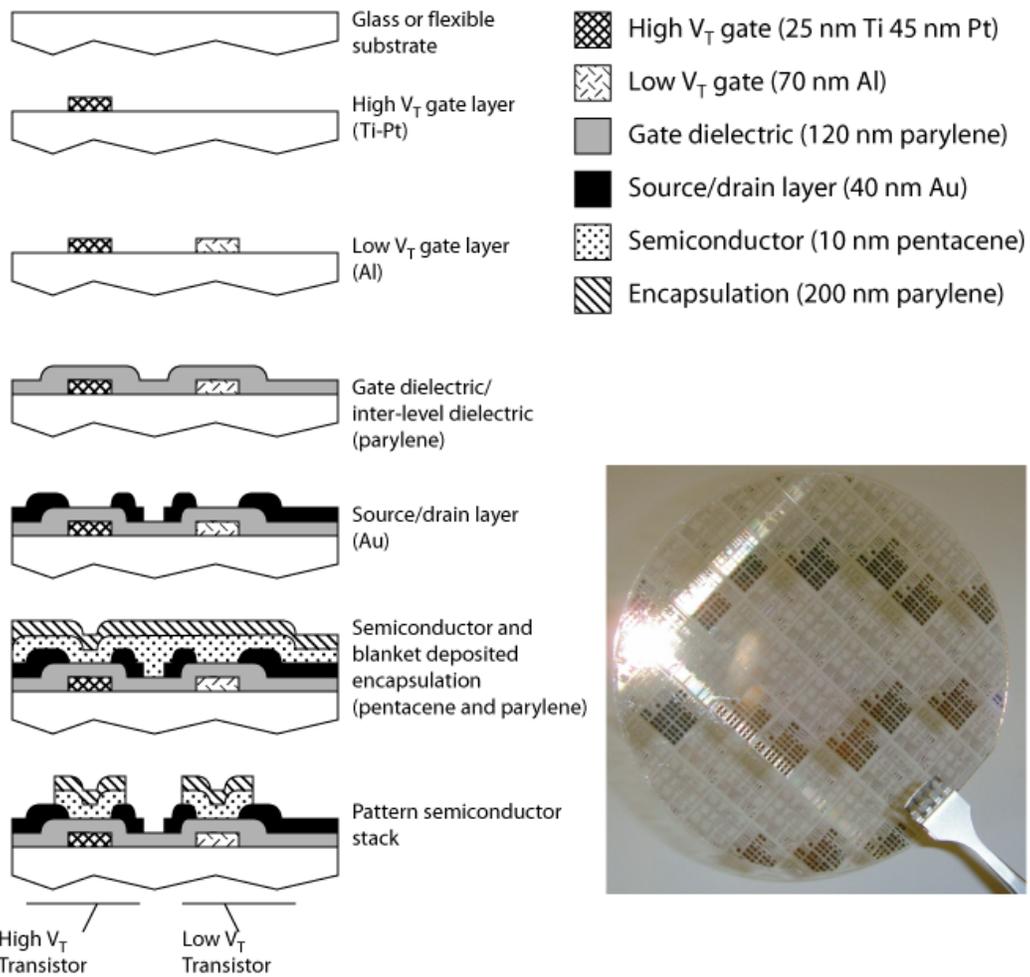


Figure 1: Process flow for the integrated dual V_T OTFT technology. All patterning steps are done with photolithography.

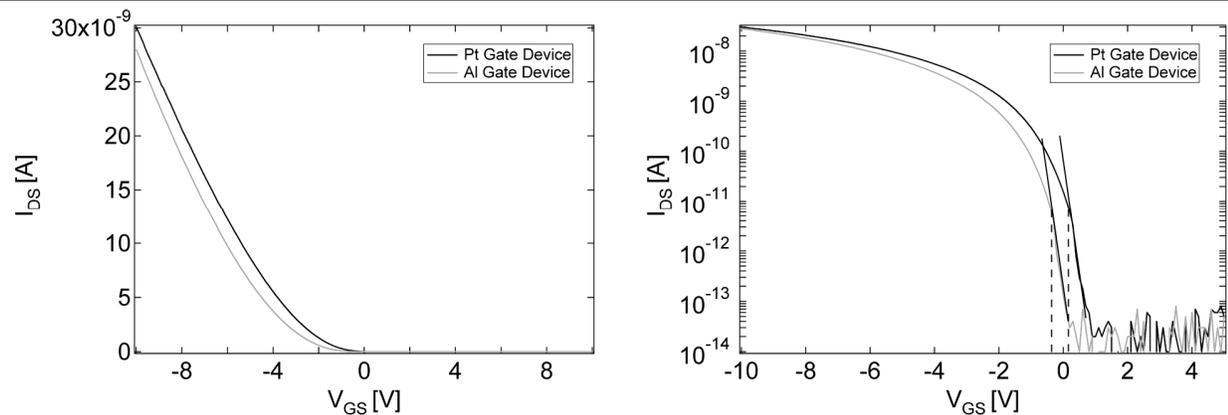


Figure 2: Linear and semi-log I-V's of Al and Pt gate devices, $W/L=200 \mu\text{m}/15 \mu\text{m}$, $V_{DS}=-1$ V. V_T 's are extracted using a straight-line fit to the subthreshold region and marking where the I-V pulls away from the fit. Here, $V_{T,Al}=-0.5$ V, $V_{T,Pt}=0.1$ V. The Pt device conducts 100x more current at $V_{GS}=0$ than the Al device.

Parameter	Wafer 1	Wafer 2	Wafer 3
Mean V_T Al - Gate	-0.43V	-0.46V	-0.72V
Std.Dev. V_T Al - Gate	0.10	0.09	0.15
Mean V_T Pt - Gate	+0.23V	+0.08V	-0.16V
Std.Dev. V_T Pt - Gate	0.10	0.08	0.15
Intra-die mean ΔV_T	+0.65V	+0.54V	+0.56V
Intra-die Std.Dev. ΔV_T	0.06	0.05	0.09

Figure 3: Statistics of V_T and ΔV_T for wafers fabricated using dual V_T OTFT process. V_T 's extracted by method in Figure 2. 4-5 dies are measured per wafer.

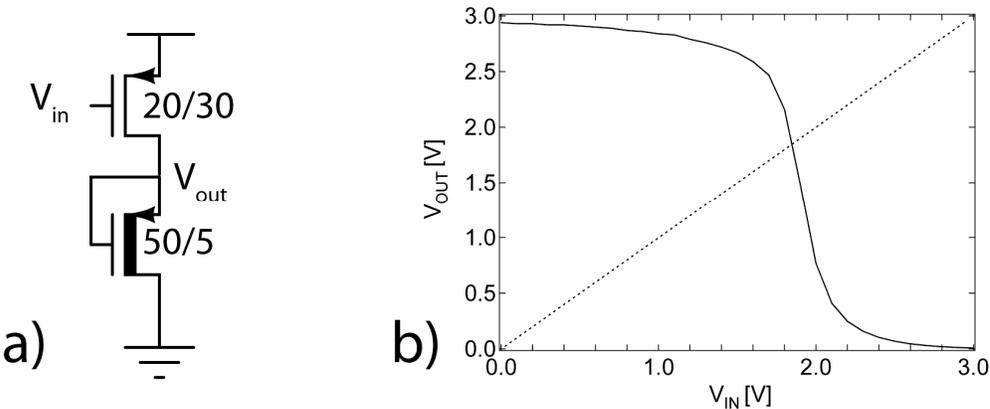


Figure 4: (a) Dual V_T inverter schematic. (b) Measured inverter characteristics, $V_{trip}=1.8$ V, $I_{trip}=8$ pA, I_{off} ($V_{IN}=V_{DD}$)=480 fA, $A_v=-7$ V/V, $V_{DD}=3$ V.

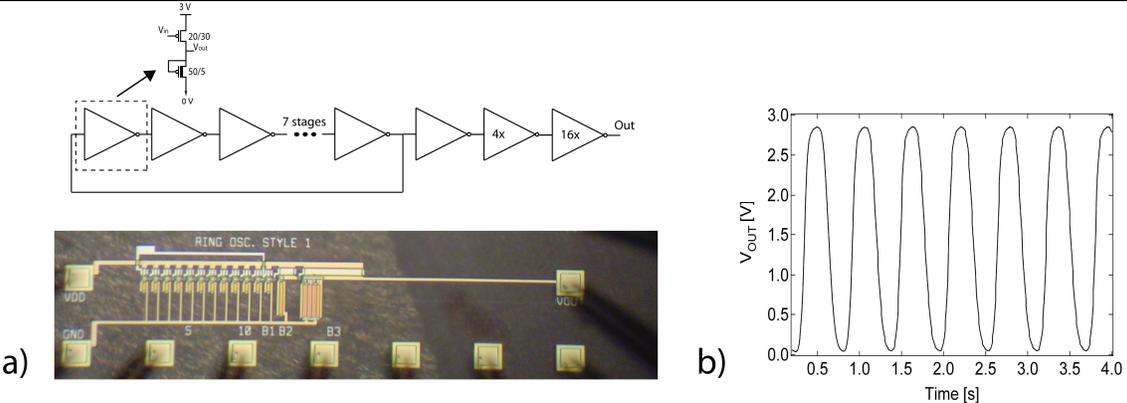


Figure 5: (a) Dual V_T 11-stage ring oscillator and output buffer. (b) The measured output waveform at a frequency of 1.7 Hz, corresponding to an inverter propagation delay of 27 ms. $V_{DD}=3$ V.